Prognostics and Health Management of Wafer Chemical-Mechanical Polishing System using Autoencoder

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Abstract—The Prognostics and Health Management Data Challenge (PHM) 2016 tracks the health state of components of a semiconductor wafer polishing process. The ultimate goal is to develop an ability to predict the measurement on the wafer surface wear through monitoring the components health state. This translates to cost saving in large scale production. The PHM dataset contains many time series measurements not utilized by traditional physics based approach. On the other hand task, applying a data driven approach such as deep learning to the PHM dataset is non-trivial. The main issue with supervised deep learning is that class label is not available to the PHM dataset. Second, the feature space trained by an unsupervised deep learner is not specifically targeted at the predictive ability or regression. In this work, we propose using the autoencoder based clustering whereby the feature space trained is found to be more suitable for performing regression. This is due to having a more compact distribution of samples respective to their nearest cluster means. We justify our claims by comparing the performance of our proposed method on the PHM dataset with several baselines such as the autoencoder as well as state-of-the-art approaches.

I. INTRODUCTION

The semiconductor industry is a multi-billions industry which manufactures nanoscale processors that is essential for modern connectivity and productivity. Large semiconductor companies such as Intel and TSMC manufacture microchips for the world's smart devices and automobiles. The Prognostics and Health Management Data Challenge (PHM) 2016¹ tracks the health state of components of a chemical

mechanical polishing (CMP) process. The ultimate goal is to develop an ability to predict the measurement on the surface wear a.k.a material removal rate (MRR) through monitoring the components health state. This ability translates to large scale cost estimates and preplanning such as raw supply estimates, delivery schedules, overhead cost estimates and etc. The semiconductor industry seeks to improve its current automated processes through using stateof-the-arts techniques in deep learning. One such process is the CMP where the prediction of material removal rate in wafer is desired. The forefront of deep learning research is often found in the domain of visual recognition. The success of deep learning approaches such as ResNet [1], VAE [2], GAN [3] in recent years in computer vision has captured the attention of many researchers from other domains. The next logical step in deep learning would be to see its deployment into the large funding sectors such as the semiconductor, automobile, military, health, finance and etc. In particular, the fabrication of wafers involves over several hundreds of processes. Each process is complex and costly to operate and not all processes are automated. Human intervention often results in productivity loss. In CMP, a skilled operator is required to periodically halt the machine in order to manually track the depthness of polished wafer surface, or the MRR. From an artificial intelligence standpoint, the CMP process contains many components health state not fully exploited by the human but exploitable by deep learning. These components health state can be grouped under the families of usage, pressure,

¹https://www.phmsociety.org/events/conference/phm/16/datachallenge



Fig. 1. Left: Reconstruction loss based autoencoder latent space is not optimized for regression. Right: Clustering in the latent space can improve regression due to the samples being more sparsely distributed (with respect to their cluster mean, as depicted in red).

slurry and rotation as seen in Fig 4. As the concatenated raw dimension in total is very large at over several thousands, many prior works turn their focus on feature selection or feature extraction, prior to regression.

Regression in CMP models the relationship between the continuous variable MRR prediction and the CMP measurement in time series. When we have an original input space or high dimensional input, standard regression model alone may not effectively capture the relationship between both input and output. Instead of pursuing the direction of more sophisticated statistical methods for regression, another common approach is to perform feature selection/ dimension reduction prior to regression. More specifically, we consider using deep learning for feature selection. However, there are two issues:

- i) Regression dataset cannot be trained easily by supervised deep learning.
- ii) Reconstruction loss alone may not be meaningful for regression.

First, regression do not rely on class labels for training. Thus, it is difficult to apply traditional deep learning such as CNN to regression datasets. Most regression dataset do not have class labels, thus the task is to more suitable for unsupervised type of deep learning such as the autoencoder. Second, the feature space trained by an autoencoder using reconstruction loss alone may not be suitable for regression because it is tasked with self correction based learning instead of specifically addressing the regression task. Typically, reconstruction loss will cause the distribution of samples in the latent space to overlap such as in MNIST [4]. In the worst scenario, we may see several suboptimal linear regression lines when performing regression in the latent space as seen in Fig 1. Thus, we require exploring other efficient loss function for the autoencoder. Specifically, we use an autoencoder loss function known as the autoencoder based clustering (ABC) to train the autoencoder [5]. This approach focuses on minimizing the difference between the distribution of the samples by the encoder and the partitioning by Kmeans in the autoencoder latent space. As illustrated in Fig 1, when we have a latent space that is optimized using class distribution, linear regression should improve since it is easier to find an optimal line due to an overall more compact representation. In a practical scenario, we may not have ground truth on how many clusters to use in the latent space. An extension is to consider the infinite Gaussian mixture model (iGMM), which simultaneously solve both model selection and clustering for ABC's deep clustering.

We demonstrated our proposed deep learning approach mainly on the PHM Challenge 2016. In the PHM dataset, our proposed approach is used as a feature selection taking the variables from the CMP process as raw inputs, before training a linear regression in the feature or latent space. We compare our proposed approach with two different baseline methods using raw inputs directly and statistical moments from the raw inputs. From experimental result, it shows that our deep learning approach outperforms both baselines. When compared to the state-of-the-arts on the PHM dataset, our method is better than methods using features from statistical moments, Random Forest to select samples from training, closed-form physics-based model as well as other non deep learning based strategies.

II. METHODOLOGY

A. Autoencoder based clustering loss

Kmeans alone only computes cluster mean and cluster assignment in the latent space and have

zero influence over learning the weight, w of the encoder. Similarly for autoencoder (AE), there is no way the encoder trained using reconstruction loss or mean square error (MSE) alone can approach a Kmeans partitioning. The autoencoder based clustering (ABC) [5] approach unites both by introducing a clustering loss. The learning in ABC is obtained through (shown in Fig 2)

- i) reconstruction loss standard mean square error on the target which is the encoder input vs the network output from the decoder.
- ii) clustering loss minimizing the error between the nearest cluster mean B^* (nearest is denoted by *) and the encoder output z, as a point in the latent space (input x that passes through the encoder).

Conceptually, the distribution of the samples in the latent space will become closer to their nearest cluster means as illustrated in Fig 1.

Formally, the cluster mean, sample in the latent space and sample x in the original dimension D are denoted by $B = \{B_k\}_{k=1}^K \in \mathbb{R}^Z, z = \{z_n\}_{n=1}^N \in \mathbb{R}^Z$ and $x = \{x_n\}_{n=1}^N \in \mathbb{R}^D$ respectively. x refers to target/ input and y is the network output. The encoder output, z is computed using the last row of eqn (1). We can replace x with z for computing the decoder. f_1 and f_2 are the tanh and sigmoid activation functions respectively. We define the ABC loss function in [5], [6] as follows

$$\mathcal{L}_{ABC} = Reconst. \ loss + clustering \ loss$$
$$= -\frac{1}{2} (x - y)^2 + \frac{1}{2} (z - B^*)^2$$
$$z = f_2 \left(\sum_{h+1} w_{h+1,h+2} \cdot f_1 \left(\sum_h w_{h,h+1} \cdot x_h \right) \right)$$
(1)

We train eqn (1) using SGD with momentum where $w_{h,h+1}$ refers to the weight between layer hand h + 1 below

$$(w_{h,h+1})_{t} = (w_{h,h+1})_{t-1} - \eta (V_{h,h+1})_{t}$$

$$(V_{h,h+1})_{t} = \rho (V_{h,h+1})_{t-1} + (1-\rho) * \frac{\delta \mathcal{L}_{ABC}}{\delta w_{h,h+1}}$$
(2)

B. Clustering approach

When we model a dataset (regardless of original space or latent space) using unsupervised learning such as Kmeans, we can represent the dataset as a set of hidden variables. These variables can in turn be used to train other task e.g. Bag-of-Words feature extraction [7], SVM-KNN classifier [8] or DP-mean clustering [9] and etc. More specifically in this paper, the cluster mean is fed into \mathcal{L}_{ABC} to train the AE.

1) Kmeans : Our main clustering algorithm is the Kmeans algorithm where cluster size K is assumed given. The cluster mean B and cluster assignment ς are point estimated as below

$$\hat{B}_{k} = \frac{\sum_{n=1}^{N} \varsigma_{nk} z_{n}}{\sum_{n=1}^{N} \varsigma_{nk}}$$

$$\hat{\varsigma}_{nk} = \arg\max_{k} \left\{ -\frac{1}{2} \left(z_{n} - \hat{B}_{k} \right)^{2} \right\} \varsigma_{nk}$$
(3)

We denoted $B = \{B_k\}_{k=1}^K \in \mathbb{R}^Z$ and $\varsigma = \{\varsigma_n\}_{n=1}^N$ where $\sum_{k=1}^K \varsigma_{nk} = 1$ and $\varsigma_{nk} \in \{0, 1\}$.

2) Infinite Gaussian mixture model: There are two key advantages over Kmeans in clustering:

- i) The number of clusters can be automatically found.
- ii) Each cluster can vary its variance.

We can define the standard mixture of Gaussian as an infinite mixture of Gaussians as follows

$$\ln p(z|B,\sigma,\pi) = \sum_{n=1}^{N} \sum_{k=1}^{T=\infty} \left\{ \ln \pi_k + \ln \mathcal{N}(z_n|B_k,\sigma_k) \right\} \varsigma_{nk}$$
(4)

We denote cluster mixture component as $\pi = \{\pi_k\}_{k=1}^{T=\infty} \in \mathbb{R}^Z$, cluster mean $B = \{B_k\}_{k=1}^{T=\infty} \in \mathbb{R}^Z$ and cluster variance as $\sigma = \{\sigma_k\}_{k=1}^{T=\infty} \in \mathbb{R}^Z$.

The expectation-maximization algorithm of eqn (4) allows us to obtain a set of closed form equations [10], [11]



Fig. 2. Backpropagation training (dashed arrows) of the raw latent space z using reconstruction loss and ABC loss. The ABC loss exploits GMM hidden variables B, σ and π for the encoder weight training. Finally, MRR regression modeling and prediction are performed in the latent space of the trained encoder.

$$\hat{B}_{k} = \frac{\sum_{n=1}^{N} \varsigma_{nk} z_{n}}{\sum_{n=1}^{N} \varsigma_{nk}}$$

$$\hat{\varsigma_{nk}} = \arg\max_{k} \left\{ \ln \pi_{k} - \frac{1}{2} \left(z_{n} - \hat{B}_{k} \right)^{2} \right\} \varsigma_{nk}$$

$$\hat{\pi_{k}} = \frac{\sum_{n=1}^{N} \varsigma_{nk}}{\sum_{k=1}^{K} \sum_{n=1}^{N} \varsigma_{nk}}$$
(5)

In the standard GMM, the significance of π is that each cluster is represented as a probability π_k as opposed to hard assignment in Kmeans.

Another important use of π is cluster pruning in [11]. In practice, for infinite GMM we cannot possibly work with an infinite number of clusters. Instead, we set T to be a sufficiently large value. Then, each iteration of eqn (5), we discard the k^{th} cluster that contains insignificant values in $\hat{\pi}_k$ and update T. At optimality, T approaches ground truth K.

Lastly as \mathcal{L}_{ABC} is unable to utilize the σ term in GMM, we simply keep it constant for each GMM cluster (a.k.a shared diagonal covariance GMM) [11].

	RMSE		
	Low Wear	High Wear	
Train	1616	166	
Valid.	354	34	
Test	354	32	
TABLE I			
PHM 2016 CHALLENGE			

III. EXPERIMENT: DEEP CLUSTERING FOR PREDICTIVE MODELING

The PHM Challenge 2016 dataset which collect measurements from a CMP process contains in total 2556 samples in Table I with mainly 18 time series variables. The evaluation of our regression model prediction is using root mean square error (RMSE) [12].

A. Feature extraction

1) Statistical moments on time series: We refer to Moment18x4 as our baseline approach using the first 4 central moments for each 18 variables, i.e mean, standard deviation, skewness and kurtosis on the PHM dataset in Fig 3. Thus, the extracted dimension is at 72.

Subsequently, we removed 6 time series variables retaining only 12 variables below, for reasons which we will discuss shortly. We then apply the first 4 central moments to these 12 which we refer to as Moment12x4 with a dimension at 48.

Usages: backing film, dresser, dresser table, membrane, pressurized sheet, polishing table.

Pressures: pressurized chamber, main outer air bag, center air bag, retainer ring, ripple air bag and edge air bag.

2) Concatenated time series : In [13] the authors used a feature extraction approach, FE2 which concatenates the edge airbag pressure and retainer ring pressure. Intuitively, this approach measures the physical contact between the table that holds the wafer (edge airbag pressure) and the wafer carrier which exert force on the wafer (retainer ring pressure). Subsequently, they extended FE2 to FE12 using the 12 variables described above. In our third baseline approach, we directly apply the raw input of FE12 to the AE. Briefly explaining FE12, it is constructed as follows: Starting from a time series of 400 dimensions per variable, we downsampled each time series by a factor of 8, to a dimension of 50, which returns a concatenated vector of 600 dimensions. We use downsampling on the time series data due to high dimensions. As a result we may tradeoff faster computation for slight loss of accuracy in MRR prediction. Lastly, we normalization the vector. We rename the FE12 appproach in [13] as RawSpace12x50 in this paper.

B. Autoencoder setup

Our architecture is using 600 - 500 - 100 for the encoder and vice versa for the decoder, taking RawSpace12x50 as raw input which has a RMSE at 7.9504 for low wear in Table II. The number of iterations for the clustering and reconstruction losses are capped at 1000 each. For regression, we find that using linear regression in the latent space works best for low wear RMSE. We used stochastic gradient ascent (SGA) with momentum (where $\rho=0.98$) as it outperforms plain vanilla SGA for MRR prediction. We use a minibatch of 2 samples for the weights training since the dataset is quite small. Our Kmeans minibatch size is 40 samples. Empirically, we found that selecting K = 2 clusters works best for the PHM dataset. Lastly for high wear, we reused the network weights we obtained for low wear.

	RMSE		
	Low Wear	High Wear	
Baseline #1: Moment18x4	12.8723	-	
Baseline #2: Moment12x4	8.4934	-	
Baseline #3: RawSpace12x50	7.9504	5.3205	
Baseline #4: PCA30	8.1794	3.9687	
TABLE II			

BASELINE METHODS

C. Baselines results

In Table II, we trained a linear regression model on the training set (we combined training and validation set) for low wear and high wear separately on Moment18x4, Moment12x4 and RawSpace12x50. The averaged result (over 10 attempts) on the test dataset shows that Moment12x4 outperforms Moment18x4 in terms of root mean square error (RMSE). We suspect that slurry and rotation families add redundancy/ noise to the regression model and actually worsen the RMSE. Overall, the RMSE is the best on RawSpace12x50. This also shows that solely using central moments is not ideal as there are loss of representation unlike using the raw dimension, with the tradeoff being a larger dimension. In our next baseline attempt, PCA30, we use prinicipal component analysis on RawSpace12x50. Empirically, we found that retaining the top 30 largest eigenvalues works best. Overall, PCA30 has lower RMSE than RawSpace12x50.

D. Reconstruction loss vs Clustering loss

Reconstruction loss alone may not be meaningful for regression because it is tasked with self correction based learning instead of specifically addressing the regression task. We setup two different AEs to have identical random initial weight. We then record the RMSE value when a regression model is trained in the latent space of each AE using identical random initial weight. Then we trained separately, i) AE with reconstruction loss and ii) AE with clustering loss using K = 2, both on the low wear training plus validation dataset in Table 1. In Fig 1 and Fig 3, the main idea is to bin the entire MRR range so that when performing clustering on each bin, the samples within each cluster should ideally be as close to the cluster center as possible. As a consequence, we minimize the within distance

	RMSE, Low Wear		
	#1	#2	#3
Initial random weights	6.5568	7.1297	6.4517
Reconst. loss	6.5934	6.9606	6.2542
Clust. loss (Kmean)	5.9704	6.5979	5.9704

RECONSTRUCTION LOSS VS CLUSTERING LOSS

of each cluster, allowing regression modeling and prediction to improve.

In Table III, we tabulate the results of regression in the latent space of i) and ii) using the test set. We observed that while reconstruction loss can reduce the RMSE on attempt #2 and #3, the improvement is not as significant as when compared to clustering loss.

E. Clustering loss: Infinite GMM vs Kmeans

When we consider the MRR histogram in Fig 3, it is not intuitive to know how many K clusters we should ideally use in the clustering loss in eqn (1), as the sample size is very low at each end of the distribution for low wear MRR. When we use too many clusters, there will be insufficient statistics for clusters with low sample count.

For the clustering loss using Kmeans approach, we ran each fixed cluster sizes from K=2 to 10. We manually found the best RMSE is at K=2. We call this value as ground truth (gt) in Table IV.

On the other hand, we employ the infinite GMM clustering for the clustering loss. We initially set T = 10. After optimization of both weight and infinite GMM via cluster pruning, we obtained the estimated clustering size to be between 3 and 4. In Table IV, we showed that the RMSE of the clustering loss using the infinite GMM outperforms the clustering loss using Kmeans. This is because infinite GMM uses soft assignment and infinite mixture as compared to hard assignment in Kmeans. A disadvantage of using this method is the additional computational overhead over the Kmeans counterpart. Furthermore on the PHM dataset, due to the comparatively small training size, the performance gained in lower RMSE is not significant.

F. Reconstruction loss + Clustering loss with Kmeans

We seek a latent space where training a regression model for prediction can improve the RMSE result.

RMSE, Low Wear					
#1		#2		#3	
ACC	\hat{K}	ACC	Ŕ	ACC	Ŕ
6.5568	-	7.1297	-	6.4517	-
5.9704	gt	6.5979	gt	5.9704	gt
5.8784	3	6.5424	4	5.9590	4
	#1 ACC 6.5568 5.9704 5.8784	R #1 ACC K 6.5568 - 5.9704 gt 5.8784 3	RMSE, Low #1 #2 ACC K ACC 6.5568 - 7.1297 5.9704 gt 6.5979 5.8784 3 6.5424	RMSE, Low Wes #1 #2 ACC \hat{K} ACC \hat{K} 6.5568 - 7.1297 - 5.9704 gt 6.5979 gt 5.8784 3 6.5424 4	RMSE, Low Wear#1#2#3ACC \hat{K} ACC \hat{K} 6.5568-7.1297-6.45175.9704gt6.5979gt5.9704 5.8784 3 6.5424 4 5.9590

INFINITE GMM VS KMEANS (CL REFERS TO CLUSTERING LOSS)

	RMSE		
	Low Wear	High Wear	
Initial random weights	6.8959	-	
Reconst. loss	6.255	-	
Reconst. + Clust. loss (Kmean)	5.6872	3.8590	
TABLE V			

PROPOSED METHOD

Our proposed approach is using an AE trained with both losses (shown in Fig 2). As mentioned earlier the proposed latent space which is trained using class information is more suitable for regression due to having a more compact distribution of samples respective to their nearest classes (shown in Fig 1).

In Table V, we trained the AE separately first with reconstruction loss. For initial random weights before using reconstruction loss, in the latent space the linear regression trained model obtained a RMSE for low wear at 6.8959. Reconstruction loss gradually reduces to 6.255 at the end of training. Training the latent space with clustering loss further reduces the RMSE to 5.6872. In the same latent space, we trained another regression model for high wear and obtained a RMSE of 3.859 on the test set. The proposed approach outperforms all baselines from #1-4 in Table 2 as well as the AEs with individual losses in Table 3.

G. Comparison with state-of-the-arts

We compare our method with some state-of-thearts CPM methods in Table VI. Our best attempt with the proposed loss function achieved an accuracy of RMSE = 4.77 for regression prediction (averaged over 10 attempts), using the approach described in Table 5. Most works [14], [15], [16], [17] extract statistical moments from the time series variables similarly to our Moment18x4. In addition some authors use features using Fourier transform. Then, they applied the feature to a base learner such as linear regression or decision tree. In [14] the authors applied the above mentioned features



Fig. 3. The MRR histograms of wafers. We observed two distributions which refer to samples with low wear ($50 \le MRR \le 100$) and high wear ($140 \le MRR \le 200$) respectively for each dataset partitioning (i.e. training, validation and test)

to a stacking of base learners trained by Extreme Learning Machine (ELM-stacking). Contrary to using statistical moments, the approach in [12] use Random Forest to select samples from training. The samples are then applied to closed-form physicsbased model to perform MRR regression. Other strategies for feature selection or extraction include using K nearest neighbor for the usage families [16], [15] and area under curve of variables [16], deep belief net (DBN) [18] and self-organizing machine variant (GMDH) [15].

We did not include the results of DBN and GMDH. We first discuss the result of [18] with a RMSE of 2.7 achieved using DBN for feature extraction and MLP for regression. They also reported that when using DBN for feature extraction and support vector regression they could achieve RMSE at 3.1. Although the authors in [18] claimed that only the variables under the usage family is critical to MRR i.e. excluding all other variables from the pressure, rotation and slurry families. However when replicating this finding, we could not reproduce this claim. Instead, we found that using both the usage and pressure families gives better result than usage family alone for our AE approach. In the approach of GMDH [15], the authors reported that when using linear regression with statistical moments, they reported a RMSE of 4.03. However, this is way lower than the RMSE of 12.87 we obtained for Moment18x4. We suspect the discrepancy between our method and [15] is likely due to the finer grouping of the PHM 2016 dataset into 3 smaller groups using additional information such as chamber ID. We did not pursue such fine grouping as it may not be realistic under practical scenario.

	RMSE
	Unknown Wear
Preston model [18]	29.5
Random Forest [12]	16.973
GBT [14]	8.252
ELM-stacking [14]	7.261
2nd Physical model [18]	7.6
Reconst. + Clust. loss (Kmeans)	4.7736
TABLE VI	

PREDICTION ERROR ON PHM 2016

IV. CONCLUSION

Feature selection is postulated as the most crucial step in the prediction of CMP process, whereby the feature space seeks to reduce the error of MRR prediction. Previous feature selection approaches rely on techniques such as statistical moments, integration under the curve, decision tree, PCA, closedform physics-based model and etc. More recent approaches use deep learning such as deep belief net and self-organizing machines. The main problem with using deep learning such as CNN for CMP process is that class label is not available. Secondly, the feature space trained using reconstruction loss may not be optimal for solving regression. Thus, we propose a feature space trained using an unsupervised type of deep learning such as an autoencoder. A recently proposed ABC clustering loss for the autoencoder seek to minimize the difference between the distribution of the samples by the encoder and the partitioning by Kmeans in the autoencoder latent space. Thus, we propose the use of ABC to train the autoencoder for regression modeling. We demonstrated our proposed deep learning approach mainly on the PHM Challenge 2016 and we were able to outperform several of our baseline approaches such as statistical moments, PCA and



Fig. 4. Variables of usages, pressure, slurry and rotation of a CMP process for a wafer sample.

raw input. When compared to state-of-the-arts on PHM, we were able to outperform techniques such as Ensemble approach, Random Forest. To the best of our knowledge, mainstream deep learning is relatively new for CMP process.

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